- 47. (Added) The method of claim 46, further comprising capping the amalgamation layer.
- 48. (Added) The method of claim 47, wherein capping the amalgamation layer comprises introducing an additional blending material to the amalgamation layer.
- 49. (Added) An electronic component formed by the method of claim 46.
- 50. (Added) The electronic component of claim 47, wherein the component comprises a circuit board, a resistor, an inductor, a capacitor, a solder point, a solder connector, a mother board or a combination thereof.
- 51. (Added) A method of forming a film, the method comprising providing a nanoporous aerogel precursor material; treating the nanoporous aerogel precursor material to form a nanoporous aerogel; providing a blending material having a reinforcing component and a volatile component; combining the nanoporous aerogel and the blending material to form an amalgamation layer; and treating the amalgamation layer to remove a substantial amount of the volatile component, thereby increasing the mechanical strength of the amalgamation layer and decreasing the dielectric constant of the film.
- 52. (Added) The method of claim 49, further comprising capping the amalgamation layer.
- 53. (Added) The method of claim 50, wherein capping the amalgamation layer comprises introducing an additional blending material to the amalgamation layer.
- 54. (Added) A film formed by the method of claim 49.
- 55. (Added) An electronic component comprising the film of claim \$2. \\
- 56. (Added) A layered material comprising the film of claim 52.

## IN THE SPECIFICATION

Insert the following before "Field of the Invention":

This application is a divisional of allowed application Serial Number 10/189,318, filed July 3, 2002.